



PATENT
97-CT-174

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
RAFFAELE ZAMBRANO)
Serial No.: 09/191,743)
Filed: November 13, 1998)
For: IN-SITU DEPOSITION AND.)
DOPING PROCESS FOR POLY-)
CRYSTALLINE SILICON LAYERS)
AND THE RESULTING DEVICE)

Group Art Unit: 2823

Examiner: M. Estrada

#14/B 9/2001
10/25/01
V. Vannall
TECHNICAL CENTER 2000

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated April 11, 2001, the due date for response to which has been extended to October 11, 2001 by the enclosed petition for extension of time, in connection with the above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents,

Washington, D.C. 20231, on 10/11/01
Date of Deposit

Stephen Bongini
Applicant, Assignee, or Representative

[Signature] 10/11/01
Signature Dated